# $Cd(S_{(1-x)} + CO_{3(x)})$  thin films by chemical **synthesis**

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A microcrystalline mixture of cadmium carbonate  $(CdCO<sub>3</sub>)$  and cadmium sulfide  $(CdS)$  were grown in the thin film format onto glass substrates by means of chemical bath. The temperature of the bath  $(T_d)$  was selected in the interval 23–80 $\degree$ C. At low temperatures, CdCO<sub>3</sub> is the compound predominant in the layers. At high temperatures CdS is the compound deposited on the substrate. At intermediate  $T<sub>d</sub>$ -values a mixture of both materials are present, i.e., the gradual transition from an insulator (CdCO<sub>3</sub>) to a semiconductor (CdS) growth occurs when  $T<sub>d</sub>$  increases. Physical properties of films were studied by means of X-ray diffraction and optical absorption. The forbidden energy band gap of direct electronic transitions ( $E_g$ ) was calculated by applying the  $\alpha^2 \propto (h\nu - E_g)$ relation to the optical absorption spectra.  $\odot$  2005 Springer Science + Business Media, Inc.

### **1. Introduction**

In the preparation of CdS or  $Cu(In,Ga)Se<sub>2</sub>$  thin films by chemical bath (CB), cadmium carbonate  $(CdCO<sub>3</sub>)$ : Otavite) is introduced as impurity into the semiconductor materials [1, 2], however this oxide is present alike a stable precipitate [2] until temperatures  $\geq$  300°C [3]. As far as we know,  $CdCO<sub>3</sub>$  has not been reported to be prepared in the thin film format. The physical properties of this oxide have been scarcely studied and, to a lesser degree, mixed with a semiconductor. The material can be useful in applications such as insulator, composite, electrode, sensor, microcapsule, among other devices. Some physical properties of  $CdCO<sub>3</sub>$ , reported by other authors, are birefringenge [4], lattice energy [5], entropy [6], phase transformations [3, 7],  $(Cd_{1-x}Ca_x)CO_3$ solid solutions [8, 9], etc. On the other hand, physical properties and applications of CdS have been widely studied and until now abundant work on them continues being reported. This work has been focused to analyze the gradual pass from CdS (semiconductor) to  $CdCO<sub>3</sub>$  (insulator) when the films are grown by the chemical bath (CB) technique, and the temperature of the bath  $(T_d)$  is chosen between 80 and 23<sup>°</sup>C. X-ray diffraction patterns show the thin films evolution from cubic (zincblende) CdS for  $T_d = 80^\circ\text{C}$ , to hexagonal (rhombohedral) CdCO<sup>3</sup> for  $T_d = 23$ °C, with mixed crystalline structures at intermediate  $T_d$  values. Furthermore, optical absorption allows to observe how the energy band gap  $(E_{\rho})$  of layers changes from 2.41 eV for CdS to 3.87 eV for CdCO<sub>3</sub>. As both chemical compounds seem do not form solid solutions between them, the study of embedded CdS particles into the transparent CdCO<sub>3</sub> material looks as an interesting subject for research. It is important to remark that nanocapsules of  $CdCO<sub>3</sub>$  are valuable for applications related to drug delivery, functional properties of adsorption of proteins and other biologically relevant molecules. These nanocapsules have been prepared by layer-by-layer deposition of alternative charged pyroelectrolytes [10]. In this way, CB could represent a simpler alternative to grow the CdCO<sub>3</sub>-nanocapsules.

## **2. Experimental**

The substrates used were commercial glass slides, which were subjected to a strong-clean process. For CB growth aqueous solutions of CdCl<sub>2</sub> (0.02 M), KOH  $(0.5 \text{ M})$ , NH<sub>4</sub>NO<sub>3</sub> (1.5 M), and SC(NH<sub>2</sub>)<sup>2</sup> (0.2 M) were prepared using deionized water. These solutions have been usually employed by us to grow CdS films on glass substrates [11, 12]. After deposition the layer were rinsed in deionized water and dried at ∼50◦C. The relative concentrations, volume proportions, deposition temperature, and pH ( $\approx$ 8.3) were kept constant during all the growth processes. Different growing temperatures were chosen in the interval 23–80<sup>°</sup>C, and each  $T_d$ was controlled within  $\pm 1$ <sup>°</sup>C. *T*<sub>d</sub>-values used were 23, 40, 50, 60, 70, and 80◦C. X-ray diffraction (XRD) patterns of samples were registered using the Cu  $K_{\alpha}$  line of a D5000 Siemens diffractometer. Optical absorption spectra measurements, carried out in the range 1.4– 4.2 eV of photon energy, were obtained by means of a Unicam 8700 spectrophotometer. Measurements of stoichiometry, within an error bar of  $\pm 1\%$ , were achieved utilizing a Voyager II X-ray quantitative microanalysis in an 1100/1110 EDX system from Noran Instruments, which was employed to record scanning electron microscopy (SEM) images of the  $CdCO<sub>3</sub>$  microcrystals. All the characterization analyses were carried out at room temperature (RT).

The chemical reactions and growth conditions for the CdS layers deposition by CB have been widely studied and reported. Nevertheless, the growth conditions for  $CdCO<sub>3</sub>$  thin films have still not been reported. In this way the chemical reactions (at RT) are:

SC(NH<sub>2</sub>)<sub>2</sub> + 2H<sub>2</sub>O 
$$
\stackrel{\text{H}^+}{\rightarrow}
$$
 2NH<sub>4</sub><sup>+</sup> + CO<sub>2</sub> $\uparrow$  + S<sup>2-</sup>  
acid medium (1)  
SC(NH<sub>2</sub>)<sub>2</sub> + 3H<sub>2</sub>O  $\stackrel{\text{OH}^-}{\rightarrow}$  CH<sub>2</sub>N<sub>2</sub> + CO<sub>3</sub><sup>2-</sup> + HS<sup>-</sup> + 3H<sup>+</sup>

 $+ 2H_2 \uparrow$  alkaline medium (2)

The  $CO_3^{2-}$  ion arises in an alkaline medium because the thiourea decomposes according to reaction 2. This ion is soluble at temperatures lower than  $75^{\circ}$ C [13]. Then, if the temperature decreases, the  $CdCO<sub>3</sub>$  proportion increases [13]. This behavior indicates that the  $CO_3^{2-}$  ion, in an alkaline environment, gradually substitutes the  $S^{2-}$  ion. Shortly, the equilibrium reactions present for  $T \leq 70^{\circ}$ C are:

$$
Cd^{2+} + S^{2-} + CO_3^{2-} + H^+ \leftrightarrow CdCO_3 + HS^- (3)
$$

$$
HS^{-} + H^{+} \rightarrow H_{2}S \tag{4}
$$

In the temperature range 75–23◦C, the reactions 3 and 4 are favored toward the right side, because the  $CO_3^{2-}$ is more soluble and, therefore, more reactive than the  $S^{2-}$  ion in that interval of temperatures. The ion  $S^{2-}$ is lesser reactive as the temperature decreases. On the other hand, when the solution containing the  $CO_3^{2-}$  ion is heated to  $80^{\circ}$ C gives place to the spontaneous formation of  $CO<sub>2</sub>$  (gas), which leaves the solution according the following reaction:

$$
H_3CO_3 + OH^- \rightarrow CO_2\uparrow + 2H_2O \tag{5}
$$

#### **3. Results and discussion**

As-grown  $Cd(S_{(1-x)} + CO_{3(x)})$  samples are strongly attached to the substrate and hard to be scratched. The different parameters involved to grow thin films by any technique are determinant to change the physical properties of materials prepared. In the chemical bath (CB) method it is well known that by changing the way and rate of stirring, different crystalline structures of

T A B L E I Growing temperature, color and concentrations of cadmium (Cd), sulfur (S), carbon (C), and oxygen (O), in atomic percent

Growing temperature $(^{\circ}C)$	Color	Concentration $(\% )$			
		Cd	S	C	Ω
80	Yellow	49.0	51.0		
70	Pale-yellow	28.2	18.4	35.4	18.0
60	Pale-yellow	24.5	17.6	39.6	18.3
50	Pale-yellow	24.8	14.6	34.3	26.4
40	Pale-yellow	19.4	3.7	35.8	40.1
23	Green-yellow	12.8	0.3	20.0	66.9

a same material can arise [14]. Other important growing parameter in CB, beside concentrations and type of substrate, is temperature, which has large influence in the sticking of material, composition, specularity, and color; e.g., CdS prepared at  $T_d = 80^\circ \text{C}$  looks, at nakedeye, intense-yellow, but when  $T_d = 70$ <sup>o</sup>C the appearance is pale-yellow. In this work, when  $T_d = 23$ <sup>°</sup>C the color of the layers is green-yellowish. The stoichiometry of CdS grown at  $T_d = 80$ °C is Cd:  $(51.0 \pm 1.0)\%$ and S:  $(49.0 \pm 1.0)\%$ . When  $T_d$  diminishes from 80 to  $23^{\circ}$ C these values diminish and carbon (C) and oxygen (O) start to increase their presence up to that S practically vanishes at  $T_d = 23$ <sup>°</sup>C. See experimental section for the processes of reaction involved in the  $CdCO<sub>3</sub>$  formation. In Table I are listed the color and composition of the samples studied.

XRD patterns are illustrated in Fig. 1 for each  $T_d$ value. The sample with  $T_d = 80$ °C is CdS in cubic zincblende (ZB) phase with an XRD maximum peak located at  $2\vartheta = 26.5^{\circ}$  (100% intensity in XRD of cubic CdS). For  $T_d = 70$ °C, the XRD maximum peak is also located at  $2\vartheta = 26.5^\circ$ , however, other small XRD lines begin to appear at  $2\vartheta = 23.5^\circ$  and  $30.3^\circ$ . This last line corresponds to line with 100% intensity of XRD-CdCO3. The experimental result indicates that already for  $T_d = 70$ °C, an important contribution of CdCO<sub>3</sub> is present into the CdS layers. As  $T_d$  goes down, the crystalline structure of layers gradually shows a larger contribution of  $XRD-CdCO<sub>3</sub>$  peaks, with the respective diminution in the intensity of the XRD-CdS lines. For  $T_d \leq 40^\circ \text{C}$ , the intensity of the main XRD-CdS peak is abruptly reduced. The critical point of the growth, i.e., that on which  $CdS$  and  $CdCO<sub>3</sub>$  are at the same proportions, was not clearly defined here and it will be subject



*Figure 1* X-ray diffraction patterns of CdS-CdCO<sub>3</sub> layers, for different deposition temperatures.



*Figure 2* SEM picture of the CdCO<sub>3</sub> microcrystals. The bar depicted in the bottom of the picture represents 10  $\mu$ m.

of a future work. For  $T_d = 23$ <sup>o</sup>C, the XRD peaks at  $2\vartheta = \{23.5, 30.3, 36.4, 43.8\}$  have been identified with  $CdCO<sub>3</sub>$  which has rhombohedral crystalline structure [15]. This rombohedral phase of  $CdCO<sub>3</sub>$  has the same aspect of the rombohedral phase of calcite  $(CaCO<sub>3</sub>)$ , i.e., SEM images of both types of microcrystalline materials show similar structures (they look cubic at first glance). See Fig. 2 for  $CdCO<sub>3</sub>$ . The reader can check Ref. 16 for CaCO<sub>3</sub>. Actually, (Cd<sub>1−*x*</sub>Ca<sub>*x*</sub>)CO<sub>3</sub> solid solutions have the same rombohedral crystalline structure in the entire range  $0 \le x \le 1$  (the otavite-calcite series). The transition from the CdS-semiconductor to CdCO<sub>3</sub>-oxide observed by the XRD analysis when  $T_d$ decreases is, in some way, supported by measurements of atomic compositions (See Table I).

Optical absorption spectra allow to calculate  $E_g$  for all the films studied. The relation for semiconductors of direct band gap employed [17] is  $\alpha^2 =$  (cte)  $(h\nu - E_{\varrho})$ , where  $\alpha$  is the optical absorption coefficient and  $h\nu$  the photon energy. In Table II are compiled the values of  $E<sub>g</sub>$ calculated for all the samples analyzed. Fig. 3a exhibits the  $\alpha^2$  versus *hv* plot for the CdCO<sub>3</sub> film. The extrapolation of the linear part of the curve intercepts the *h*ν-axis at 3.87 eV, which equals  $E<sub>g</sub>$  of CdCO<sub>3</sub>. In the inset of Fig. 3a, the same procedure is illustrated for the *Eg* value of CdS, which is in agreement with the reported value (2.42 eV) for cubic CdS at RT [11]. In Fig. 3b is displayed the calculation of  $E<sub>g</sub>$  for the sample grown with  $T_d = 50^\circ \text{C}$ . In the inset of Fig. 3b, the obtaining of  $E_g$  for  $T_d = 40^\circ \text{C}$  is included. The region where the curve is a straight line and its extrapolation until the energy axis for the determination of  $E<sub>g</sub>$  in the stoichio-

TABLE II Temperature of deposition and forbidden energy band gap (*Eg*) of layers

Growing temperature $(^{\circ}C)$	$E_{g}$ (eV)
80	2.41
70	2.50
60	2.50
50	$2.47 - 3.60$
40	$2.42 - 3.63$
23	3.87



*Figure 3* (a)  $\alpha^2$  versus *hv* plot for  $T_d = 23$ °C. The material deposited has been identified as CdCO<sub>3</sub> with  $E<sub>g</sub> = 3.87$  eV. The inset exhibits the same type of plot for CdS ( $T_d = 80^\circ \text{C}$ ) with  $E_g = 2.42 \text{ eV}$ . (b)  $\alpha^2$  versus *hv* plot for  $T_d = 50^\circ \text{C}$ . The material is a mixture of CdS and CdCO<sub>3</sub>. The inset displays the same type of plot for  $T_d = 40$ <sup>o</sup>C. In these case two values of  $E_g$  are obtained.

metric films of  $CdCO<sub>3</sub>$  and CdS, shown in Fig. 3a and in its inset, respectively, are clearly defined. However for samples with  $T_d = 40$  and 50<sup>°</sup>C, whose fitting for  $E_g$ determination are depicted in Fig. 3b, the linear region for extrapolation is not unique as in Fig. 3a. According with the inset of this figure, at  $T_d = 40$ <sup>o</sup>C, for instance, two linear parts can be extrapolated and two values of direct  $E_g$  are defined. All this behavior is an indication that for  $T_d \leq 50^{\circ}$ C, both materials are segregated one from the another one. Each crystalline phase can include some small density of impurities taken from the aqueous ambient, as it can be deduced from the variation of the corresponding  $E_g$  values, when  $T_d$  is different from 80 or 23<sup>°</sup>C. In Table II, for  $T_d = 40$  and 50 $\degree$ C, two values of  $E_g$  are listed.

## **4. Conclusions**

Supported by our experimental results, we can ensure that the growth of thin films from a semiconductor material (CdS) to a dielectric one  $(CdCO<sub>3</sub>)$  has been obtained. The band gap of this oxide is direct and has a value of  $E_g = 3.87$  eV. For low CdCO<sub>3</sub> concentrations, CdS films show an increase of the band gap energy.  $CdCO<sub>3</sub>$ , which is useful for many applications, become interesting because the physical properties in the form of thin film, also to study the properties of nanocrystals of CdS embedded inside of the volume.

## **Acknowledgements**

The authors are grateful with M. Guerrero, R. Fragoso and I. Negrete for their technical assistance. This work was partially supported by CONACyT, México.

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*Received 17 February and accepted 17 December 2004*